

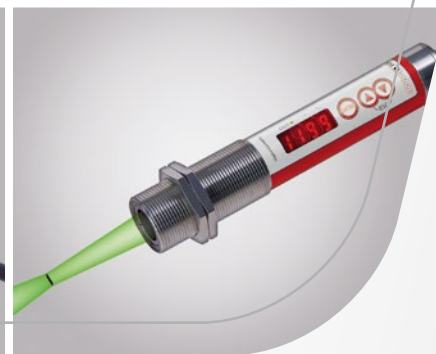
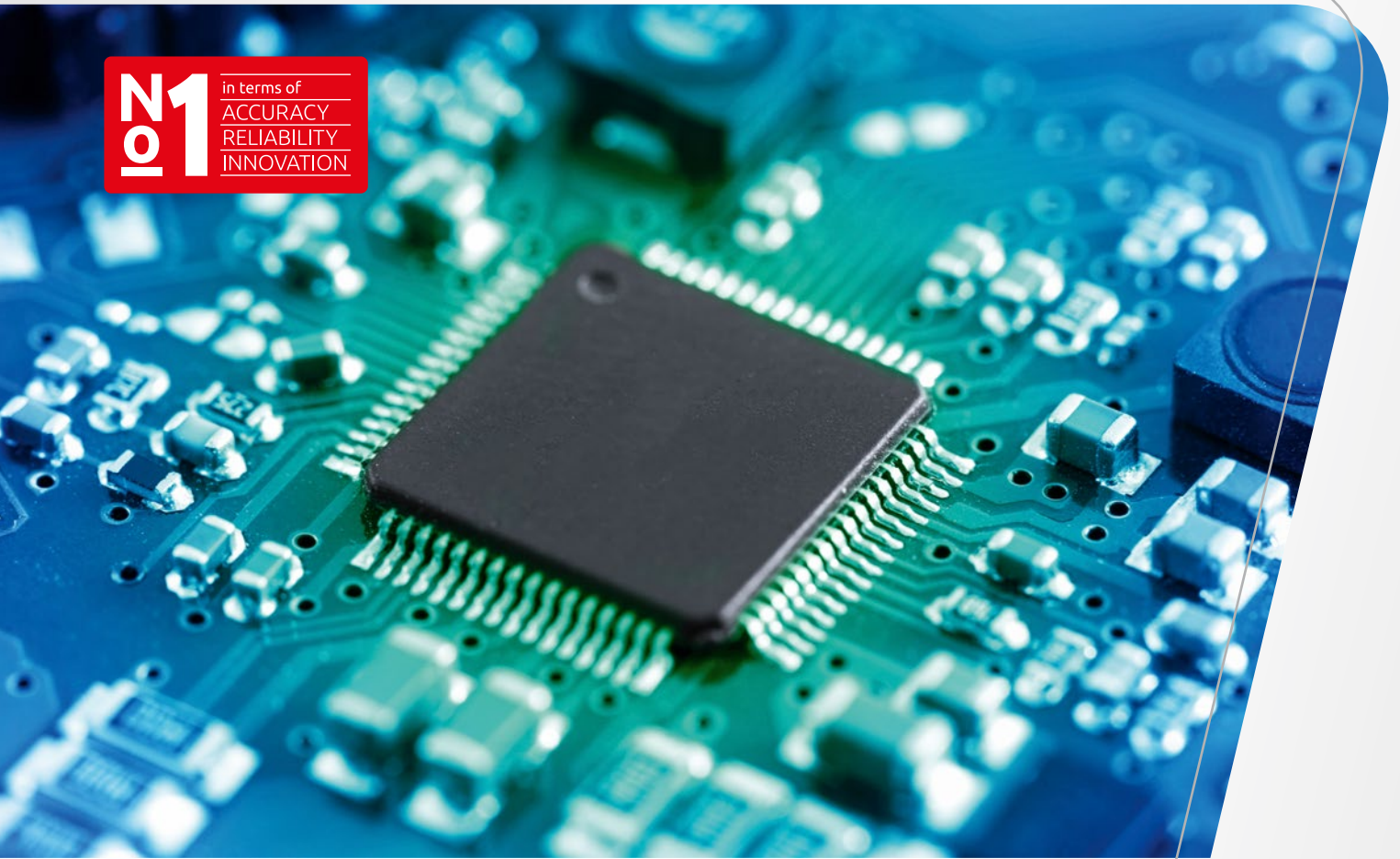
KELLER

*infrared
temperature
solutions*

ITS

NO1

in terms of
**ACCURACY
RELIABILITY
INNOVATION**



Application Semiconductor industry

Optical temperature measurement in
crystal growth and wafer processing

Products and processes in the semiconductor industry

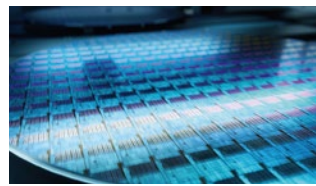
The semiconductor industry is a rapidly growing market with increasing demands on the performance and production costs of its products, such as **photovoltaic cells, microchips, LEDs and lasers**. The process chains for producing these products include the extraction of a pure semiconductor substrate with a crystal lattice that is as flawless as possible and its further processing. This further processing includes the thermal treatment and coating of wafers.

Importance of temperature measurement

The process temperature is a decisive factor in the semiconductor production. In crystal growth and wafer processing, specific temper-



Crystal growth



Wafer processing

ature ranges must be observed in order to avoid defects and thus achieve a high yield. Real-time temperature measurement is thus of crucial importance. Optical temperature measurement with pyrometers is the ideal method to quickly determine the exact process temperature from the infrared radiation of the semiconductors without contact. The demanding and multiple measurement tasks require optimally customized pyrometer solutions.





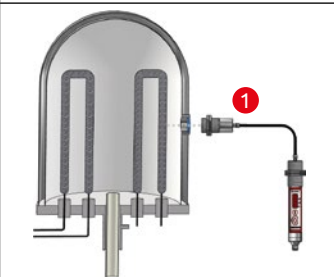
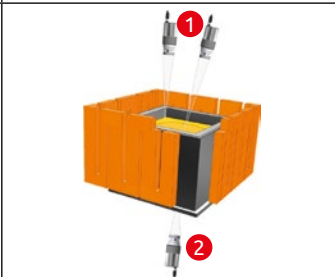
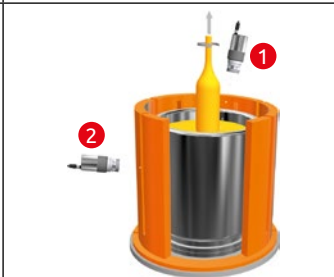
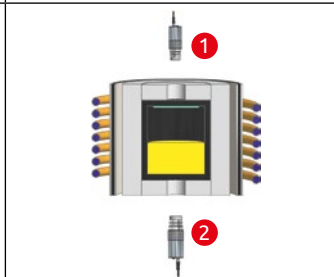
KELLER pyrometers



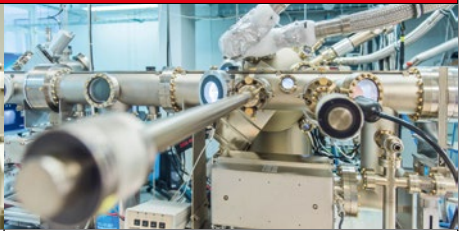
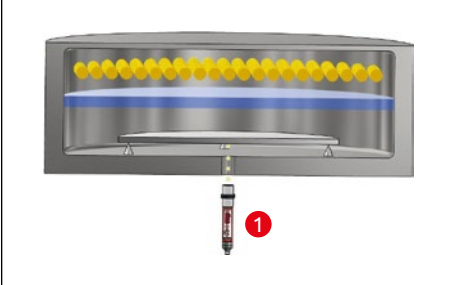
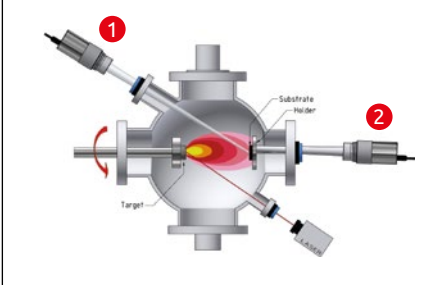
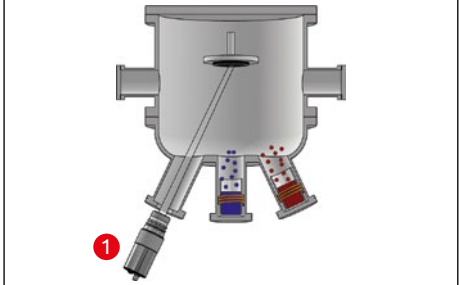
KELLER ITS has more than 50 years of experience in precise optical temperature measurement and offers special pyrometers for a wide range of processes in the semiconductor industry.

Special features




- Measuring ranges from -30 to 3,500 °C
- Calibration at the process temperature
- Long-term stability due to minimal self-heating

Processes and solutions

Crystal growth			
			
Siemens process	Multicrystalline silicon	Czochralski method	SiC (silicon carbide)
			
Process requirements			
<ul style="list-style-type: none"> • Installation of the electronics outside the Ex zone of the plant • Initially thin Si rods require a high-resolution lens with a small measuring field diameter 	<ul style="list-style-type: none"> • Required high measuring accuracy due to calibration at the process temperature • Long-term stable sensors measure reliably over the entire process time 	<ul style="list-style-type: none"> • Required high measuring accuracy due to calibration at the process temperature • Long-term stable sensors measure reliably over the entire process time • Small heating zones require a high-resolution lens with a small measuring field diameter 	<ul style="list-style-type: none"> • Small openings in the insulation require a narrow field of view and a sighting device with precise detection of the measuring position and size of the measuring field • Long-term stable sensors measure reliably over the entire process time • Insensitivity to dirt due to two-colour measuring method
KELLER solutions			
PKF 66 AF 1	PX 44 AF 4	PX 44 AF 4	PX 45 AF 1

Heat treatment	Coating	
		
RTP (Rapid Thermal Processing)	PLD (Pulsed Laser Deposition)	MBE (Molecular Beam Epitaxy)
		
Process requirements		
<ul style="list-style-type: none"> • Semiconductor wafers require a spectral sensitivity of the pyrometer below the band gap • High-intensity lenses enable the measurement of low process temperatures 	<ul style="list-style-type: none"> • Pulsed laser radiation requires blocking filters and sensors that are not affected by the laser • Small substrates require high-resolution lenses with a small measuring field diameter 	<ul style="list-style-type: none"> • Coated substrates require a short-wave spectral sensitivity of the pyrometer • Changing coating materials require large measuring spans with consistently high measuring accuracy
KELLER solutions		
PA 38 AF 10, PK 35 BF 1	PX 29 AF 21	PA 20 AF 1, PA 38 AF 10

Product overview

	Designation	Measuring range	Wavelength	Special features	Other features
	PX 44 AF 4	750 - 2400 °C	0.95 / 1.05 µm	<ul style="list-style-type: none"> • Special calibration for silicon (Si) enables very high measuring accuracy at the process temperature • Precise alignment 	<ul style="list-style-type: none"> • Focusable interchangeable lenses • Optionally with through-the-lens sighting, laser pilot light or video camera • Analog current output and digital interface
	PX 45 AF 1	900 - 3200 °C	0.9 / 1.05 µm	<ul style="list-style-type: none"> • Narrow beam path • High temperature two-colour pyrometer • Special calibration for SiC 	
	PX 29 AF 21	180 - 1200 °C	1.8 - 2.2 µm	<ul style="list-style-type: none"> • Special blocking filter and sensor against the influence of external radiation 	
	PX 20 AF 1	210 - 2000 °C	1.1 - 1.7 µm	<ul style="list-style-type: none"> • Large temperature measuring range • High-resolution lens for measuring the smallest objects 	
	PA 38 AF 10	450 - 1800 °C	0.82 - 0.93 µm	<ul style="list-style-type: none"> • Special wavelength for silicon wafers • High-intensity lens for measuring low temperatures 	
	PK 35 BF 1	450 - 1400 °C	0.82 - 0.93 µm	<ul style="list-style-type: none"> • Special wavelength for silicon wafers 	
	PKF 66 AF 1	700 - 1800 °C	0.95 / 1.05 µm	<ul style="list-style-type: none"> • Fibre optic cable pyrometer with optical measuring head • Short-wave and narrow-band for temperature measurement of silicon (Si) • High optical resolution 	

Further measuring devices with temperature ranges from -30 to 3,500 °C can be found on our website www.keller.de/its

KELLER

Creating Solutions


infrared
temperature
solutions

ITS



- Headquarters
- Sales and Service Center
- Sales abroad



 **IO-Link**

PROFI
BUS

Keller HCW GmbH
Infrared Temperature Solutions (ITS)
Carl-Keller-Straße 2-10
49479 Ibbenbüren-Laggenbeck
Germany

www.keller.de/its
Tel. +49 (0) 5451 850
Fax +49 (0) 5451 85412
its@keller.de

Sales and Service Center

Frankreich
www.keller.de/its
Tel. +33 (0) 951 453050
its@keller.de

Italien
www.giga-tech.it
Tel. +39 (0) 296489130
contatti@giga-tech.it

Österreich
www.sensotec.at
Tel. +43 313 551 650
office@sensotec.at

Russland
www.ampermetr.com
Tel. +7 343 384 55 45
info@ampermetr.com

Spanien
www.umi.es
Tel. +34 94 446 62 50
comercial@umi.es

China
www.keller-its.cn
Tel. +86 (0) 10 828 679-20
keller@germantech.com.cn

Indien
www.keller-itsindia.com
Tel. +91 (0) 98841 11025
info@keller-itsindia.com

Korea
www.ultratec.co.kr
Tel. +82 (0) 70 8282 5979
ellen@ultratec.co.kr